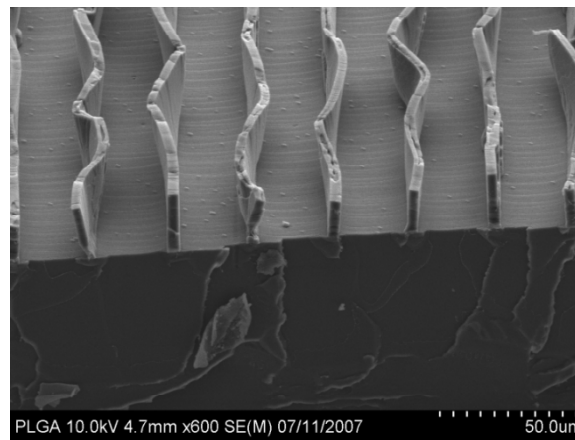
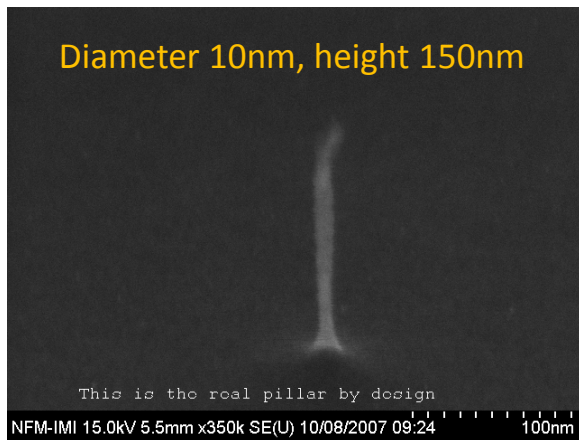
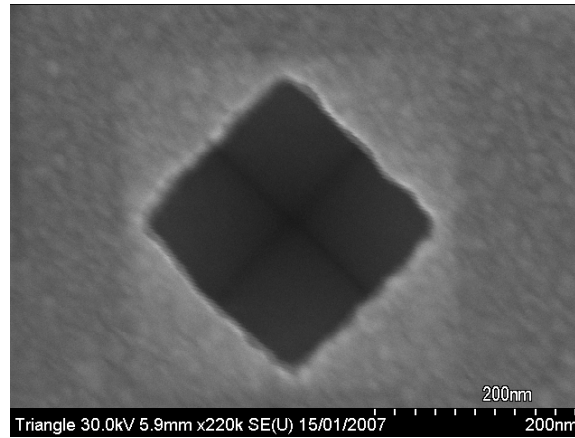
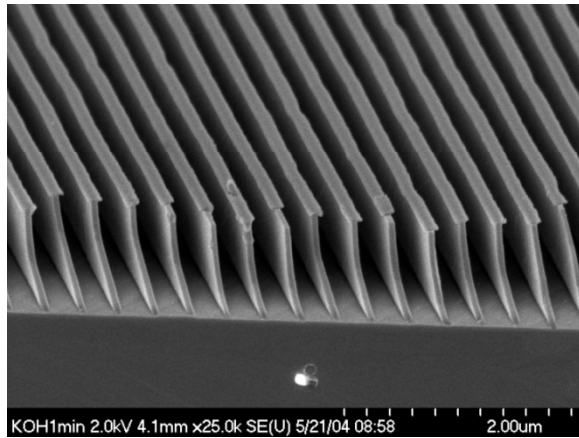
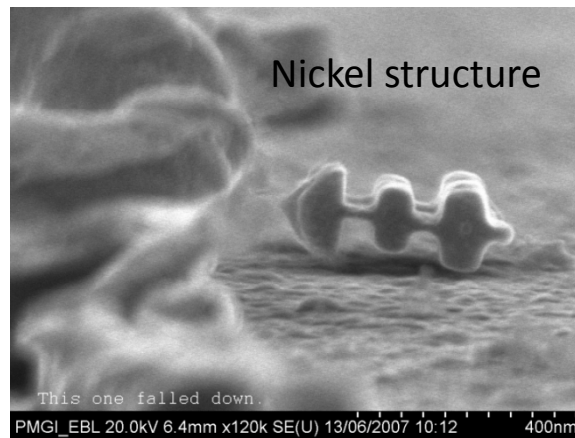
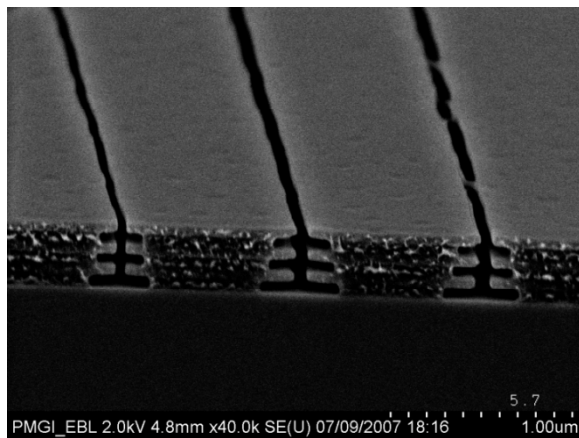


Periodic two-dimensional nanostructures fabricated by nanoimprint lithography (hot embossing lithography) from a (one-dimensional) grating mold that was made by interference lithography. Here are nano-pillars, crescents, rings, disks, triangles, holes, all with 200nm period.



High aspect ratio structures by anisotropic wet KOH etch, RIE of silicon, and hot embossing of PLGA that is a biodegradable polymer.



Nanostructures fabricated by electron beam lithography using multi-layer resist stack, and electroplating.